## THE UNRESPATES PATENT AND TRADEMARK OFFICE

n re application of: Shigeomi Chono, et al.

Attorney Docket No.: YMUCP002

Application No.: 10/814,110

Examiner: D.T. Nguyen

Filed: March 30, 2004

Group: 2871

Title: LIQUID CRYSTAL FLOW FORMING MECHANISM, METHOD OF FORMING SAME, AND OBJECT MOVING MECHANISM USING

LIQUID CRYSTAL FLOW

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents, Alexandria, Virginia 22313-1450 on January 5, 2006.

Signed: Dun

Deborah Neill

## INFORMATION DISCLOSURE STATEMENT 37 CFR §§1.56 AND 1.97(b)

Commissioner for Patents Alexandria, VA 22313-1450

Dear Sir:

The references listed in the attached PTO Form 1449 may be material to examination of the above-identified patent application. Applicants submit these references in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make these references of official record in this application.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

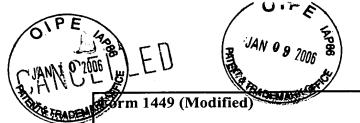
This Information Disclosure Statement is believed to be filed before the mailing date of a first Office Action on the merits. Accordingly, it is believed that no fees are due in connection with the filing of this Information Disclosure Statement. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. YMUCP002).

Respectfully submitted,

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**Information Disclosure Statement By Applicant**  Atty Docket No.

Application No.: 10/814,110

YMUCP002

Applicant:

Shigeomi Chono, et al.

Filing Date

Group 2871

(Use Several Sheets if Necessary)

March 30, 2004

**U.S. Patent Documents** 

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub- class	Filing Date
	A						
	В						
	C						

Foreign Patent or Published Foreign Patent Application

Examiner		Document	Publication	Country or		Sub-	Trans	lation
Initial	No.	No.	Date	Patent Office	Class	class	Yes	No
	D	2001-260100	25/09/01	Japan			X	
	E	2001-013895	19/01/01	Japan			X	
	F	06-046584	18/02/94	Japan			X	
	G	11-230023	24/08/99	Japan			X	
	Н	08-270615	15/10/96	Japan			X	
	I	3005263	10/05/94	Japan			X	

## **Other Documents**

Examiner						
Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication				
	J	PCT/JP02/10129, English translation of Japanese examiner's comments.				
Examiner		Date Considered				

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.